
Achieving Small Dimensions with an
Environmentally Friendly Solvent:
**Photoresist Development Using
Supercritical CO₂**

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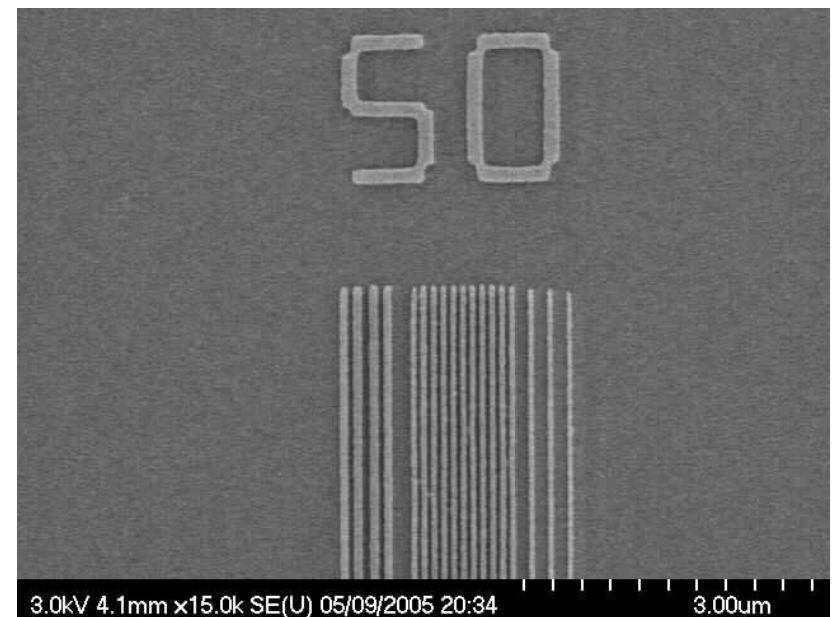


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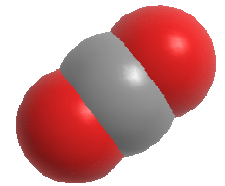
Outline

- Supercritical CO₂ as a development solvent
 - Advantages
 - Use with polymeric photoresist systems
- Small molecule photoresists
 - Potential advantages
 - Solubility in scCO₂
 - Patterning performance

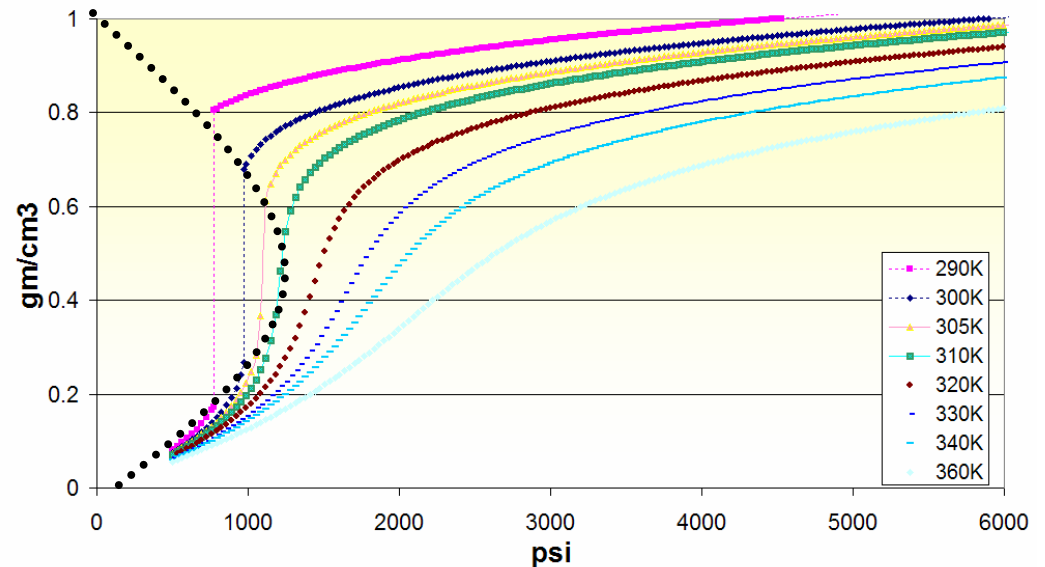
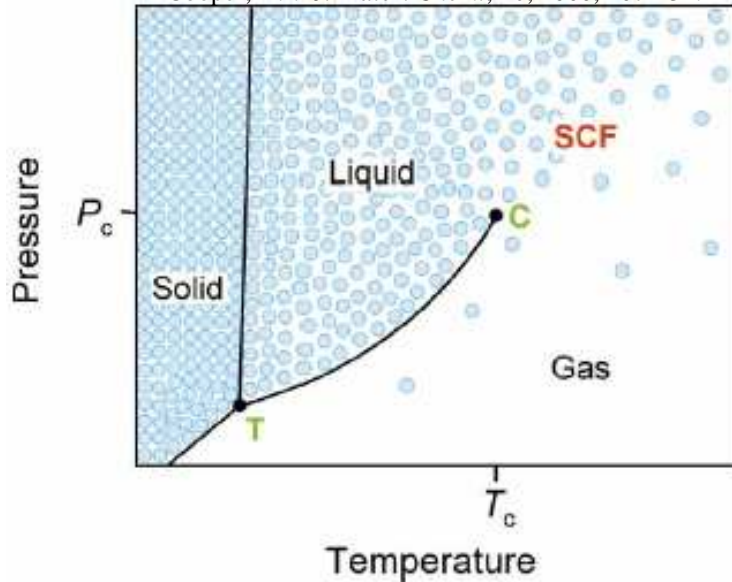


Supercritical CO₂ Basics

- Supercritical CO₂
 - Tunable, non-polar solvent with the ability to dissolve select non-polar materials
 - $T_c = 31^\circ\text{C}$, $P_c = 1070\text{psi}$ (77 bar)



Cooper, A.I. *J. Mater. Chem.*, **10**, 2000, 207-234.



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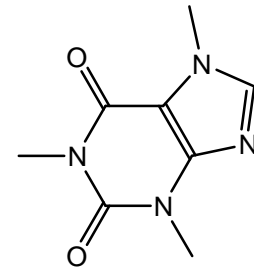
Supercritical CO₂ in Industry

- Extraction of essential oils from organic matter
 - Cinnamon, ginger, sandalwood, etc
 - Pharmaceutical applications

Flavex®



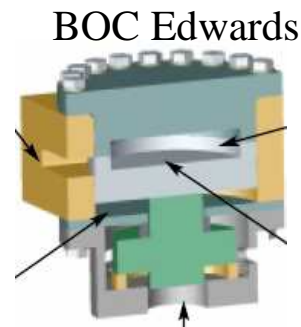
- Decaffeination of coffee
 - CO₂ replaced CH₂Cl₂ as solvent, removed only caffeine



- Dry Cleaning
 - Addition of surfactants



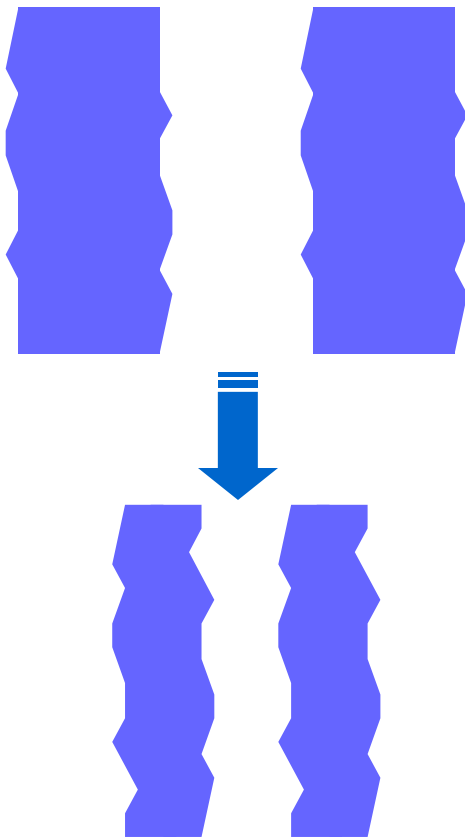
- **Wafer cleaning**
 - BOC Edwards DFP-200
 - Critical Point Dryer



Next Generation Lithography: Key Problems

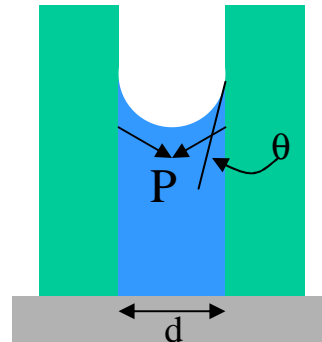
Pattern Variations

< 3nm for 32nm node



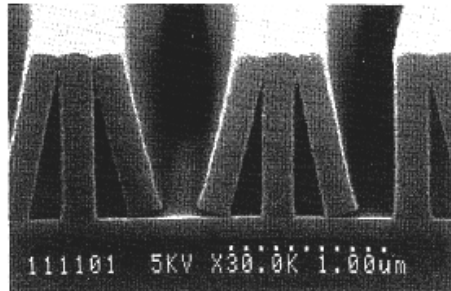
Pattern Collapse

Reduce surface tension



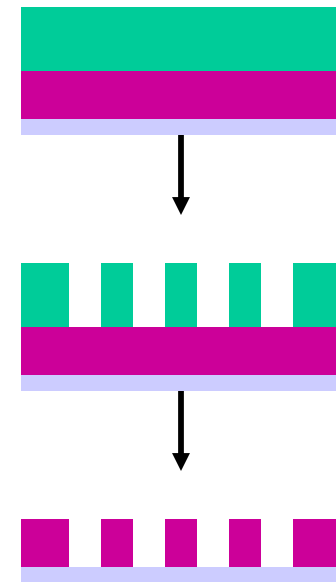
$$P = \frac{\sigma}{R} = \frac{2\sigma \cos \theta}{d}$$

@ 50nm L/S, aspect ratios >2:1 collapse w/water



Non-polar Materials

Low-κ applications



Lack of appropriate non-polar developers → Must use multiple subtractive steps

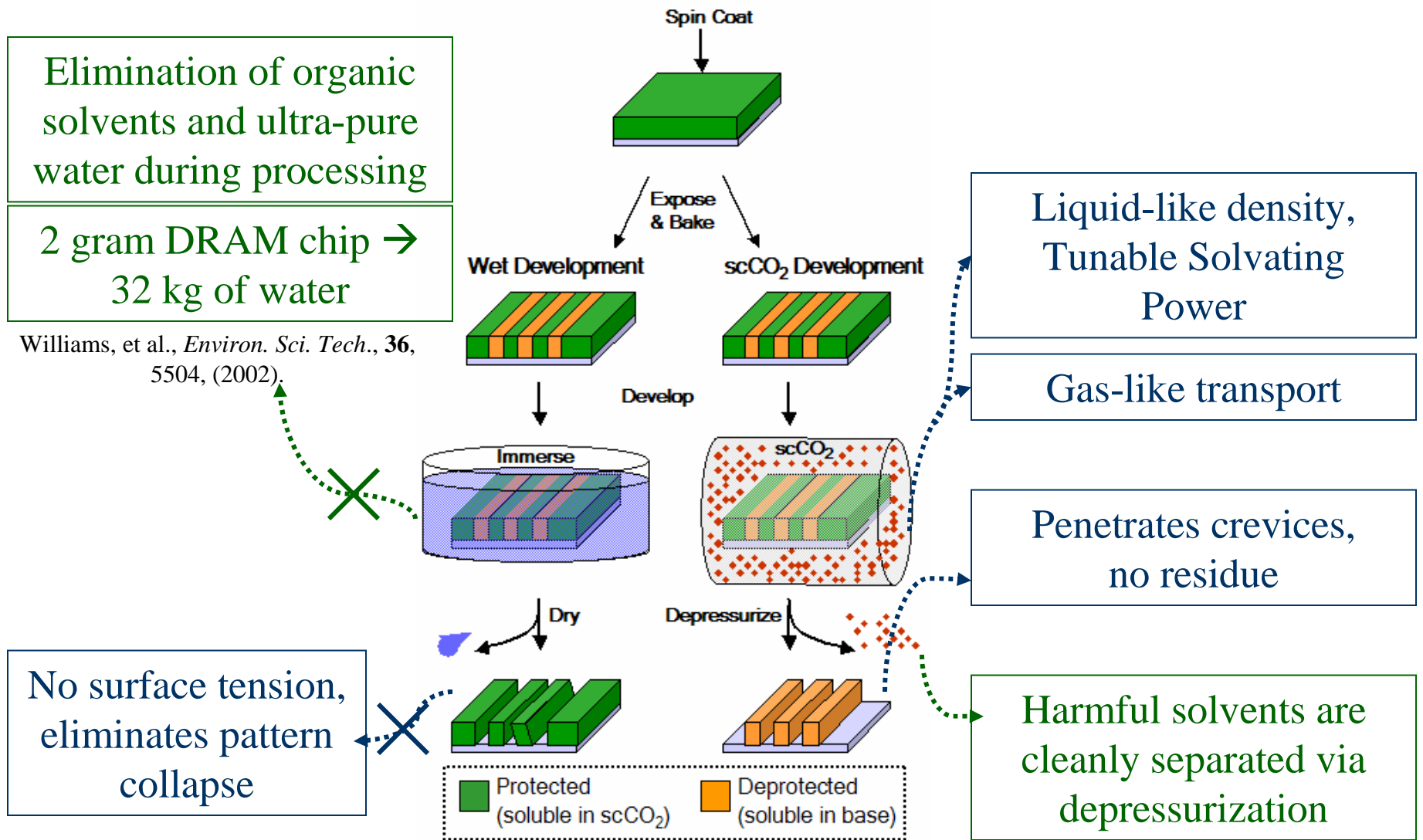
T. Tanaka, M. Morigami, N. Atoda,
JJAP, **32**(pt1, 12B) 6059 (1993).



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Advantages of Supercritical CO₂ Development

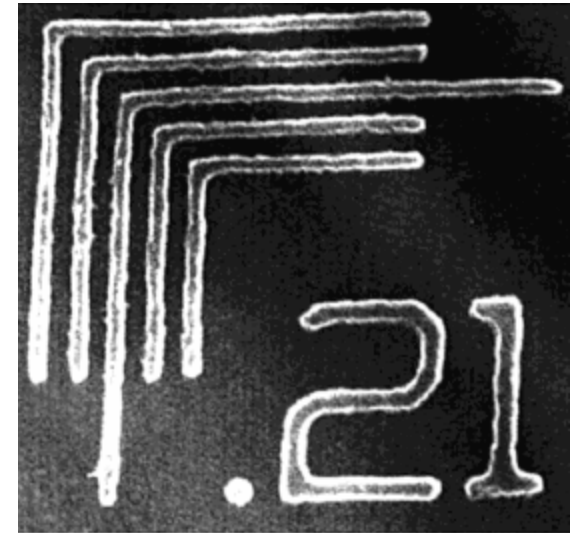
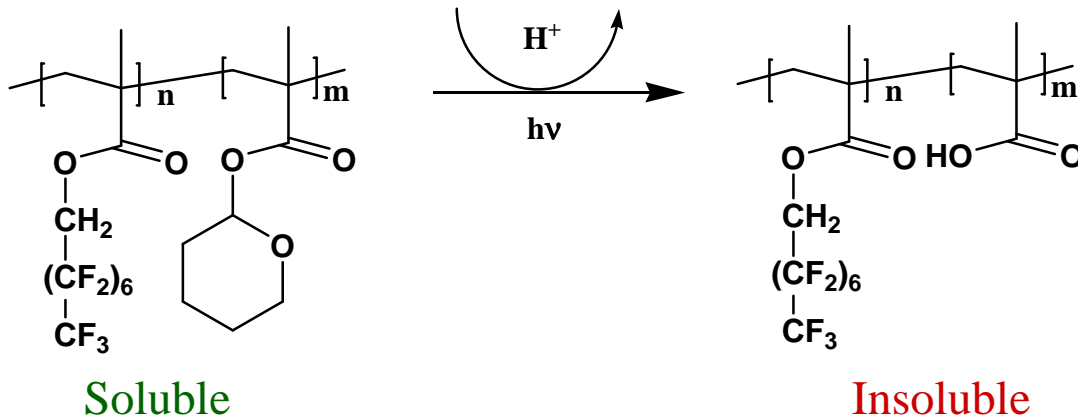


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Fluorinated scCO₂ Soluble Photoresists

- First platform for soluble polymeric photoresists
 - Copolymerize traditional photoresist monomers with fluorinated monomers
- Negative tone



Sundararajan, et al. 193 nm exposure.

- Block copolymer (Cornell) and random copolymer (UNC) versions demonstrated.

N. Sundararajan, S Yang, K Oglno, S Vallyaveetfl, J Wang, X Zhou, C. K. Ober, S. K. Obendorf, and R. D. Allen, *Chem. Mater.* 12, 41 (2000).
D. Flowers, E N Hogan, R Carbonell, mad J. M. DeSImone, in Proceedings of SPIE, 4690, 419 (2002).

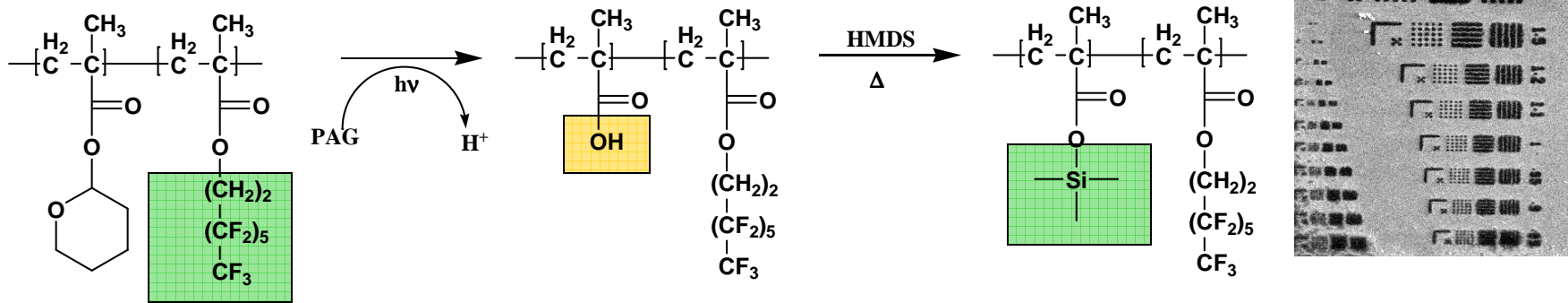


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Positive Tone Resists for scCO₂ Development

Two-step positive-tone



Pham, V Q.. et al., *Chem. Mater.* 15(26), 2003, 4893-5.

- Balance must be struck between resist solubility (increase F) and contrast (increase functionality)



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Resist Fluorination

- Advantages
 - High transparency at 193 nm, 157 nm exposure wavelengths
 - Library of fluorinated monomers
 - Simple to increase scCO₂ solubility with monomer inclusion
- Disadvantages
 - Low plasma etch resistance of F-containing structures
 - Surface compatibility: low surface energy
 - Low glass transition temperatures (T_g)
 - Difficult to keep sharp pattern shape
 - Low contrast

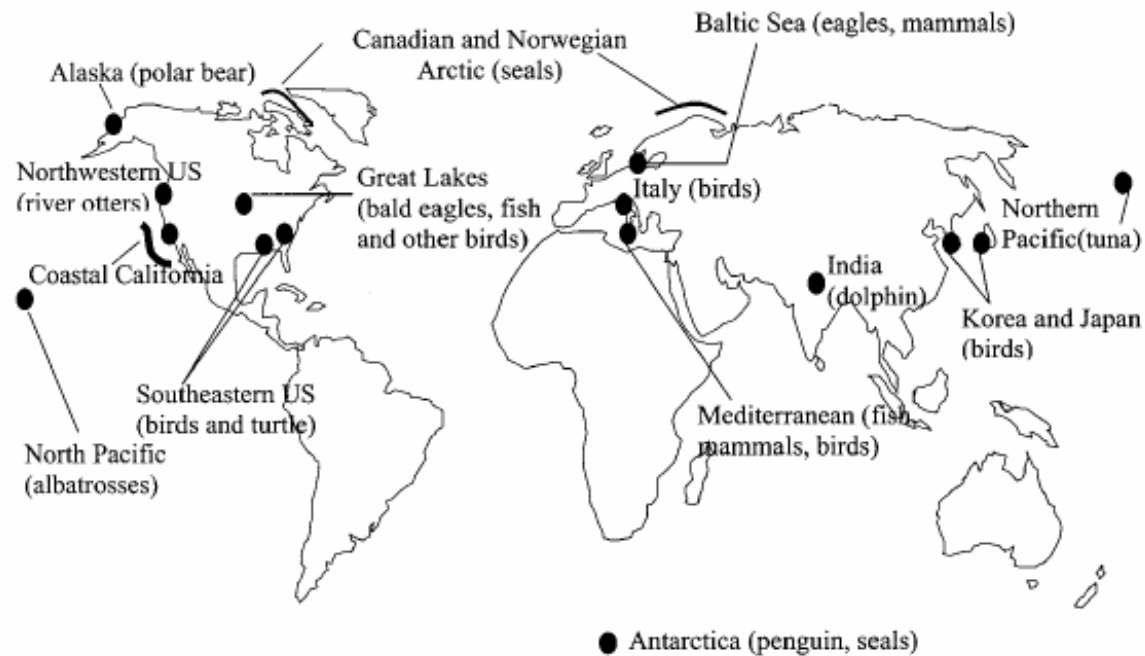


Reduce Fluorination

Perfluorinated octyl compounds have been shown to bioaccumulate and disrupt cellular functions

Environmentally friendly? → reduce need for fluorination

Giesy J P; Kannan K, Environ. Sci. & Tech. (2001), 35(7), 1339-42

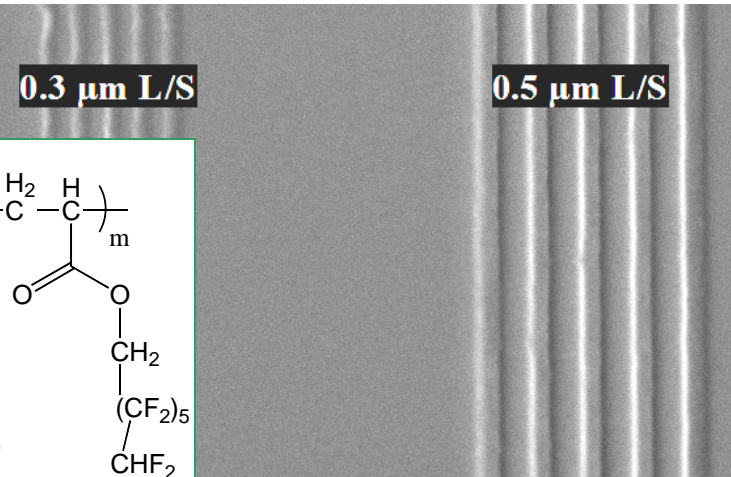
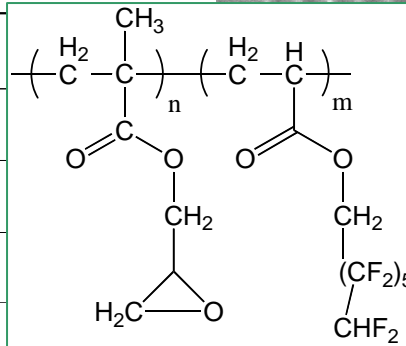
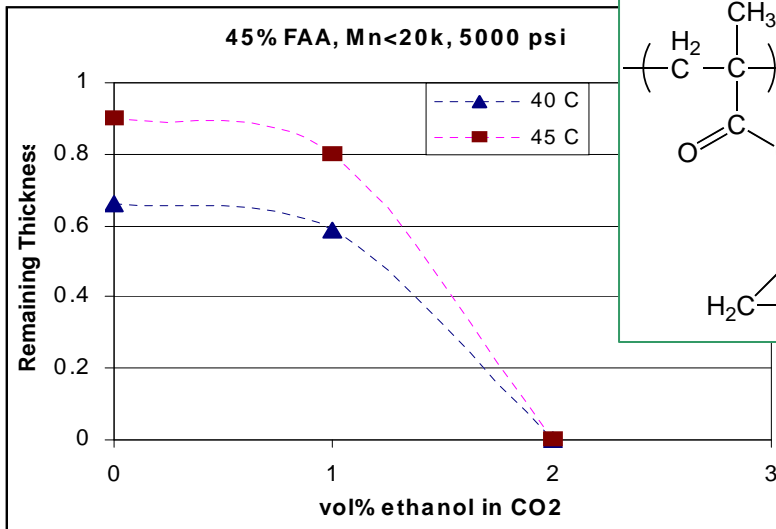


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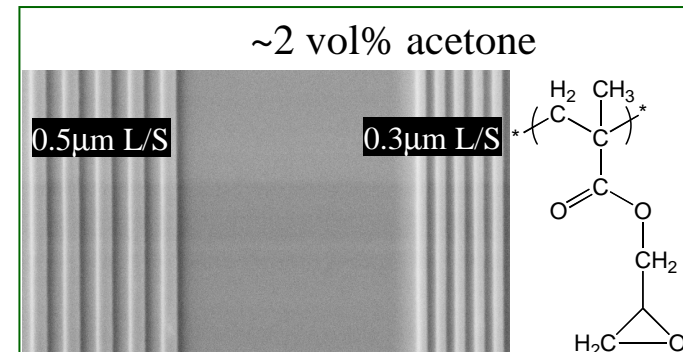
Reducing Fluorination: Using Cosolvents

- Increase solvent density
- Tune polarity of fluid
- Specific interaction with a comonomer



2 vol% ethanol (1.5mol%, 1.6wt%)
in scCO₂
P = 5000 psi, T = 45°C, t = 10 min

- 1 vol% **ethanol**...very little effect
- 2 vol% **ethanol**...100% removal



Mao, Yu; Felix, N. et al., *JVST B.*, **22**(5), 2004, 2473-8.



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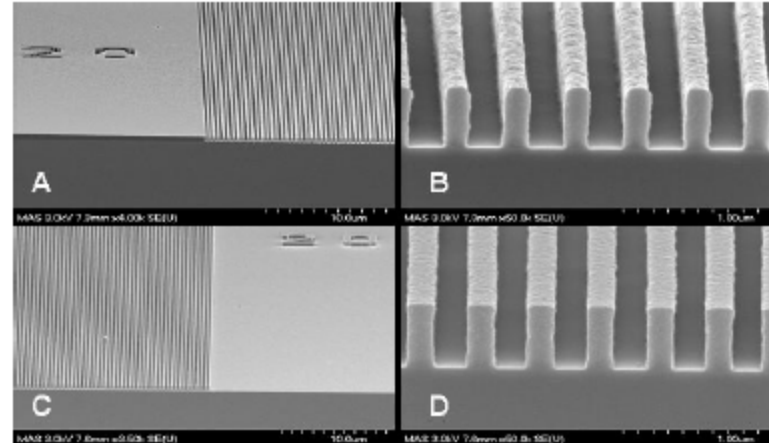
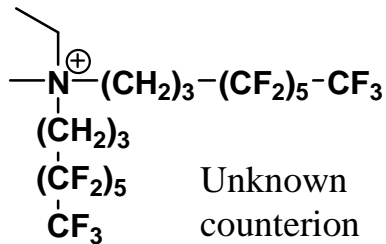
Additives for Processing Conventional Resists

- Patent literature full of examples of surfactant libraries used for scCO₂ dissolution of photoresists
 - Fluorinated or hydrocarbon tails
 - Polar or carboxylate heads
 - Mostly seen for pattern cleaning/drying
- Recent work by Micell Technologies on reactive ionic additives to impart scCO₂ solubility to conventional photoresists



'CO₂ Compatible Salts'

- Rather than ionic surfactants, reactive fluorinated salts added to solution
 - Interact with weak acidic groups of photoresist to impart solubility
 - Due to lower amounts of acidic groups, unexposed regions gain sufficient solubility first
 - Presence of generated acid in exposed regions inhibits reaction with photoresist



Aqueous TMAH develop

CO₂/CCS develop

Wagner, M., DeYoung, J., and C. Harbinson, SPIE v 6153 I 2006, p 61531.

DeYoung, J., et al., SPIE v 6153 I 2006, p 615345.

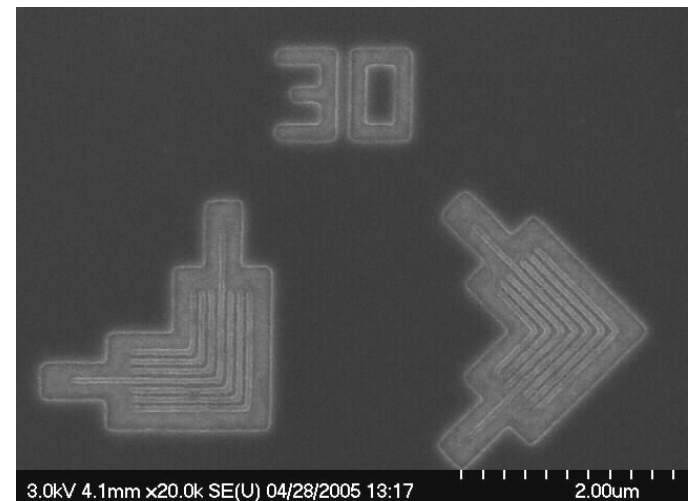
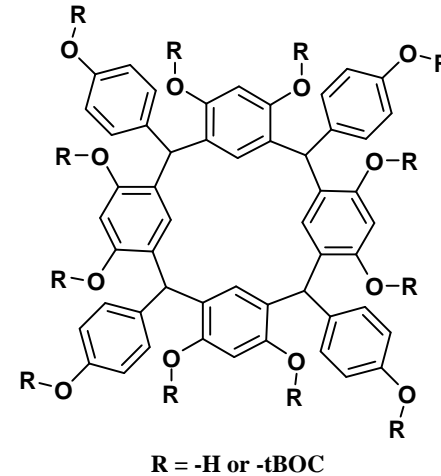


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Molecular Glass Photoresists

- Small molecule size ~1-2nm
- Well defined molecular structures
 - No distribution of mass
- Low tendency towards crystallization
 - bulky irregular shape or different conformation states
- Strong intermolecular attractive forces for high T_g
 - Specific interactions such as H-bonding



S. W. Chang, R. Ayothi, D. Bratton, D. Yang, N. Felix, H. B. Cao, H. Deng and C. K. Ober, *J. Mater. Chem.*, **16** (2006), 1470-74.

Images obtained at Lawrence Berkeley National Laboratories by EUV microexposure tool



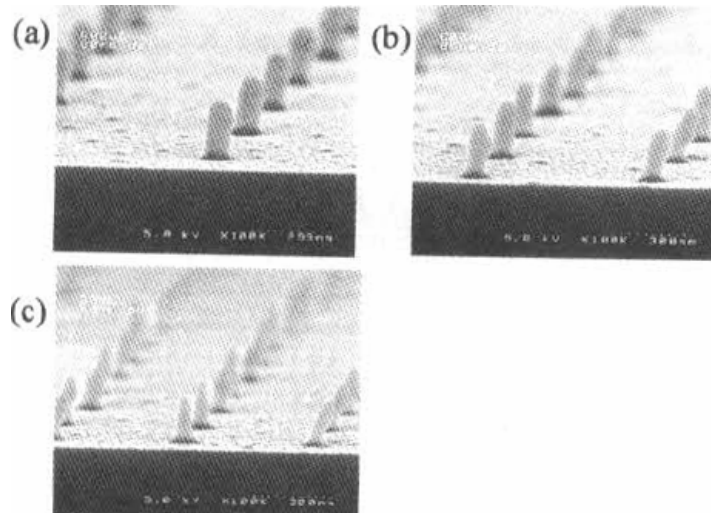
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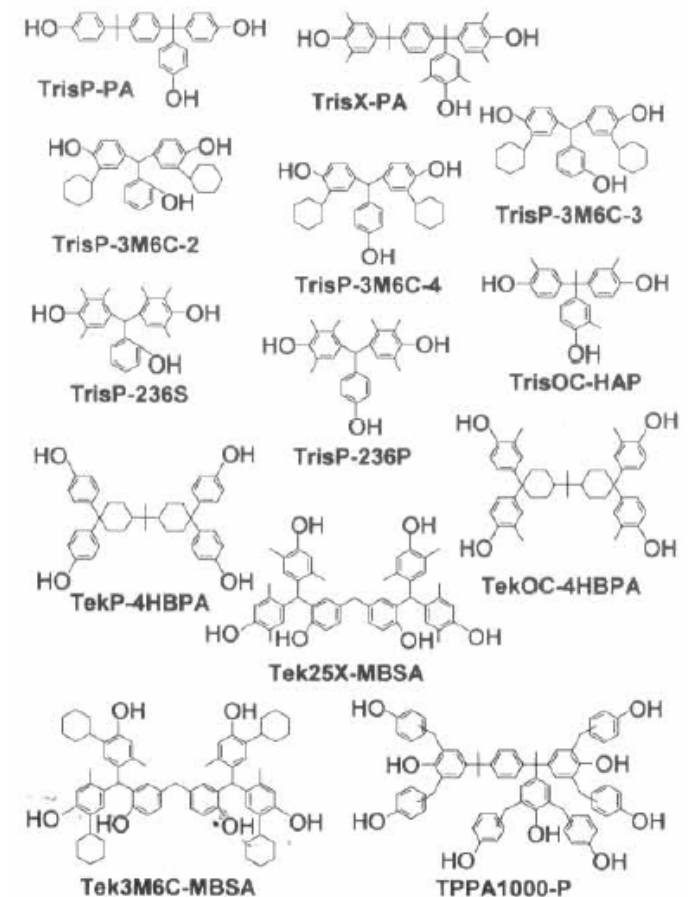
Molecular Glass Resist Solubility in scCO₂

- Due to their small size, these resist materials have the potential for scCO₂ solubility w/o fluorine
- Balance between size and polar functionality

Recent example



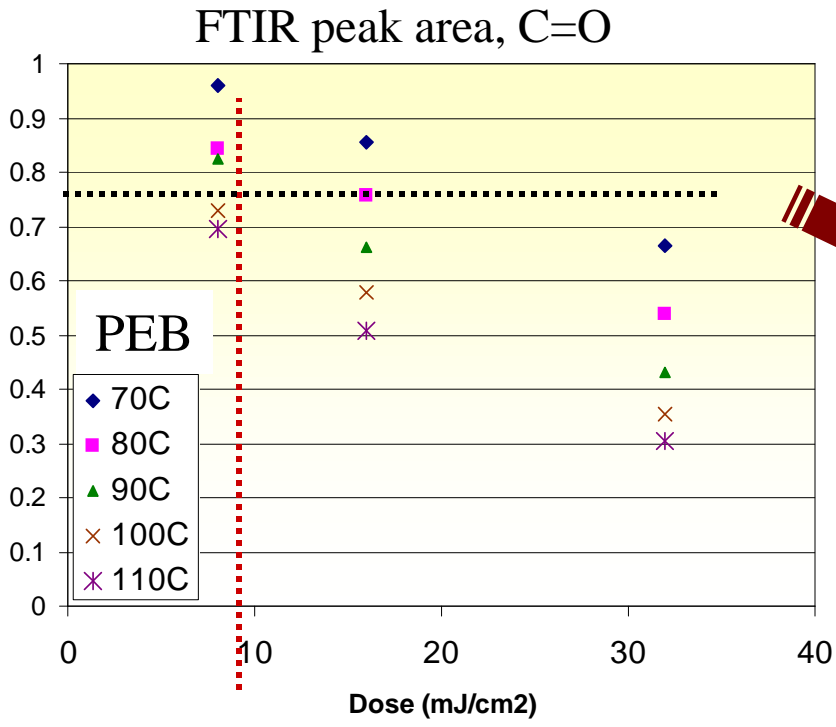
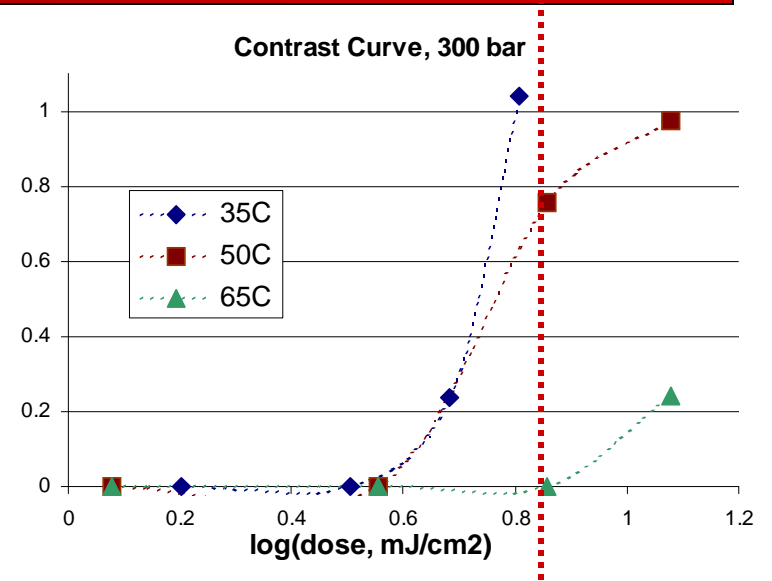
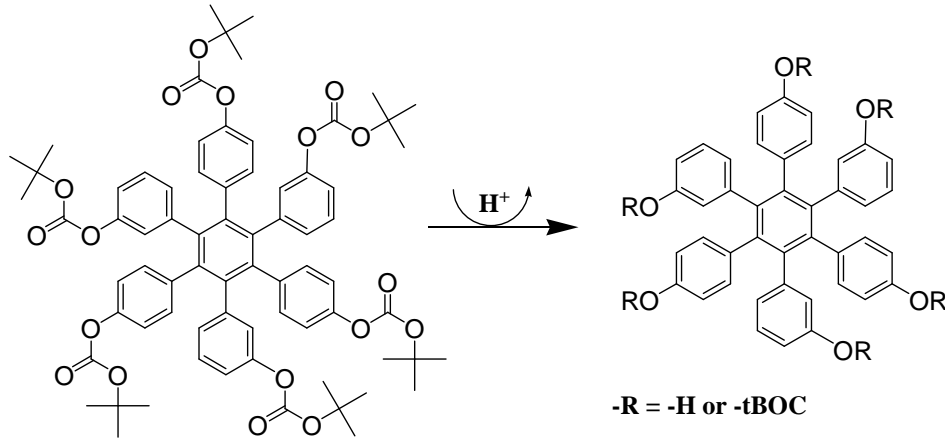
H. Shiraishi, J. Yamamoto, T. Sakamizu, *J. Photopolym. Sci. Technol.* **19**(3) (2006), 367-372.



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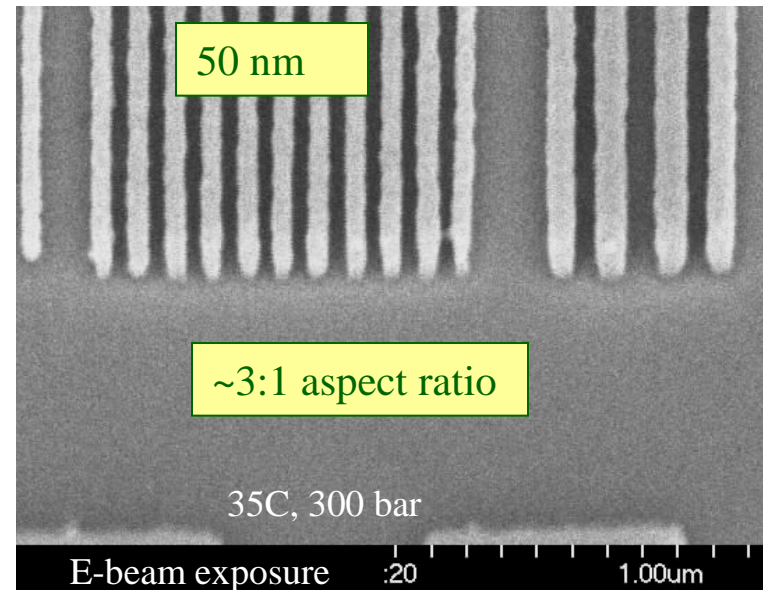
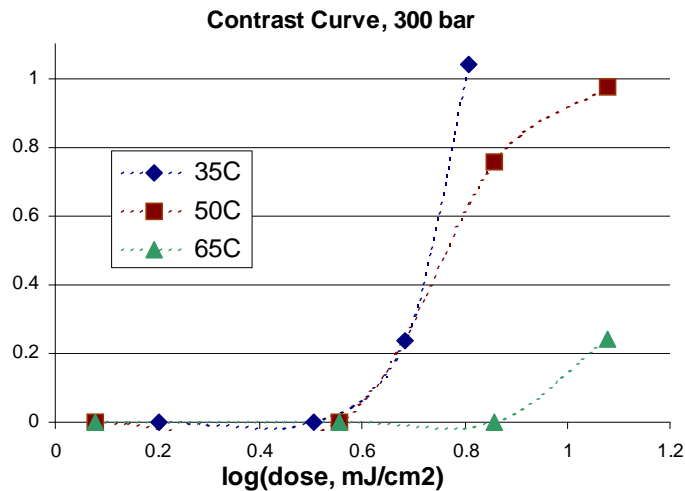
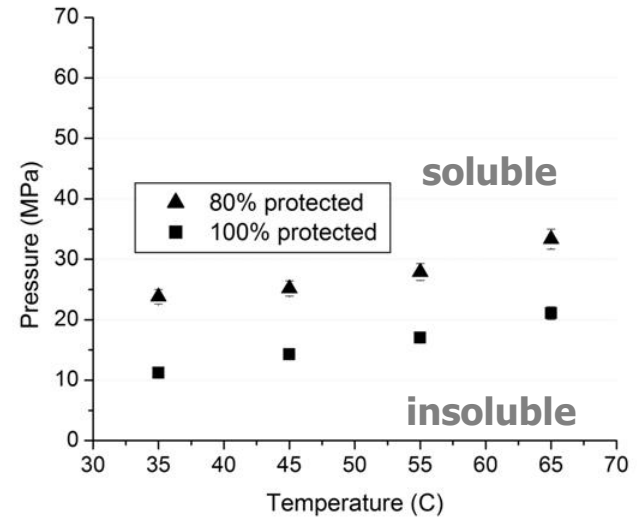
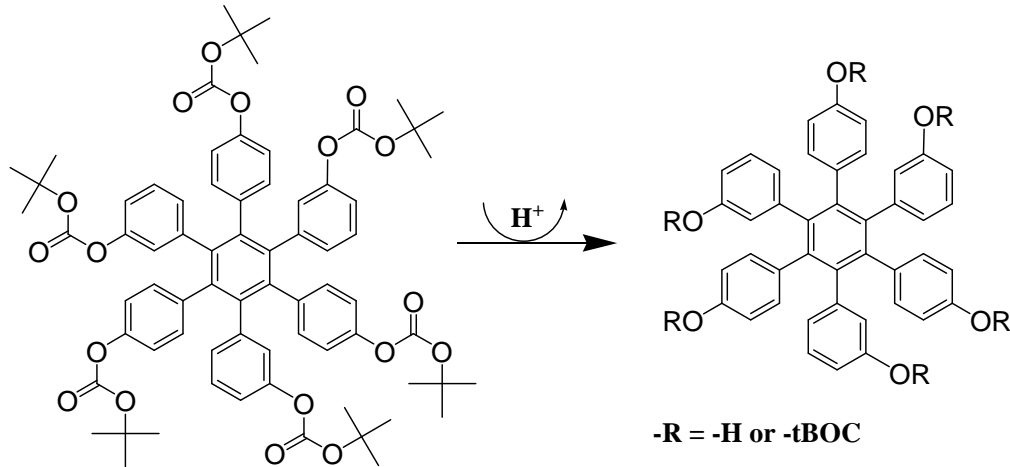
Solubility Switching



From FTIR data, solubility switch happens below <80% tBOC protection



High Resolution MG Resist for Supercritical CO₂



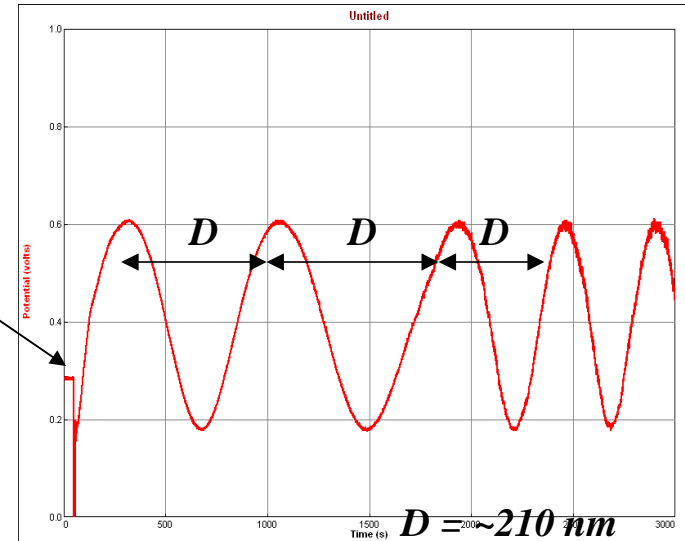
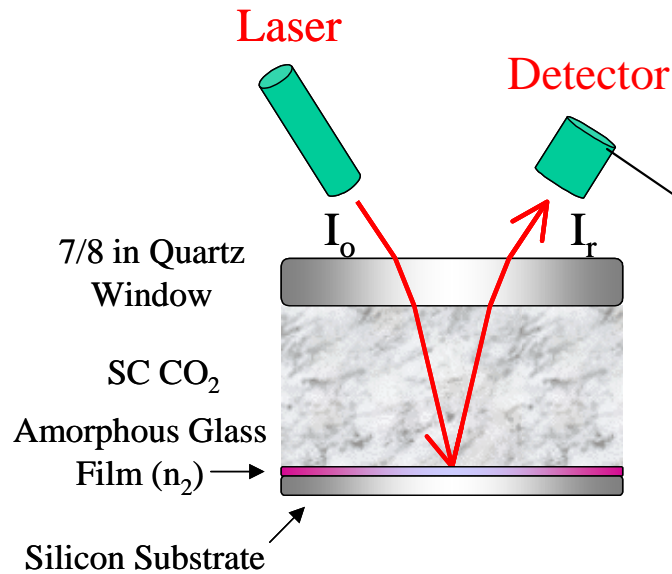
Felix, N. M, Tsuchiya, K., and C. K. Ober, *Adv. Mater.*, 18(4), 2006, p 442-446.



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Dissolution Rate Measurements

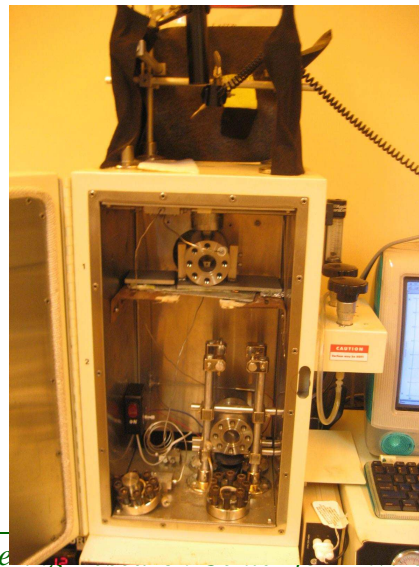


$$D = \frac{\lambda}{2\sqrt{n_2^2 - n_1^2 \sin^2(\theta)}}$$

$$\lambda = 632.8 \text{ nm}$$

n_1 = solvent refractive index

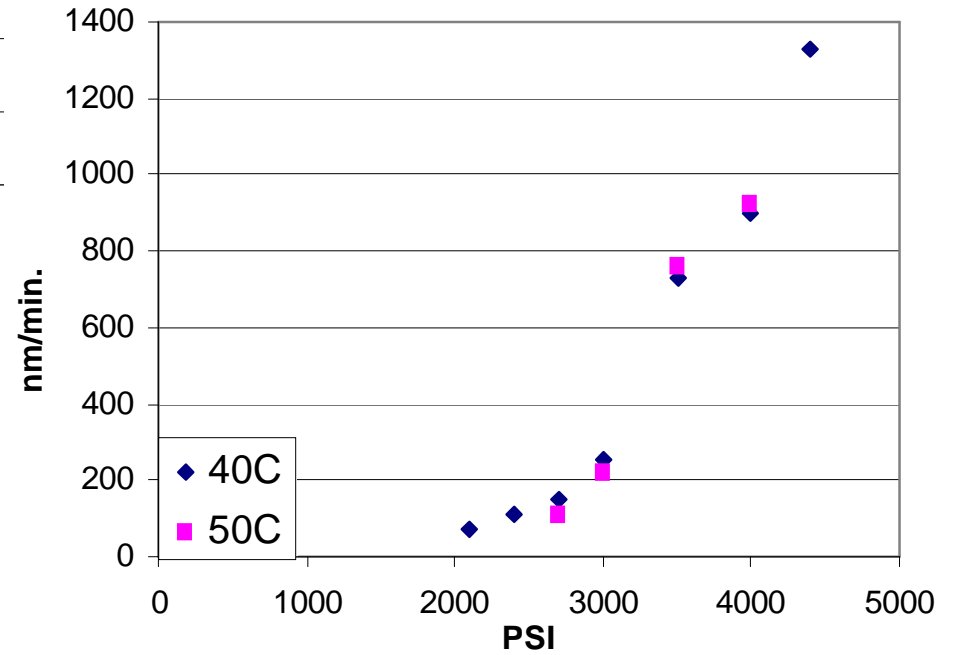
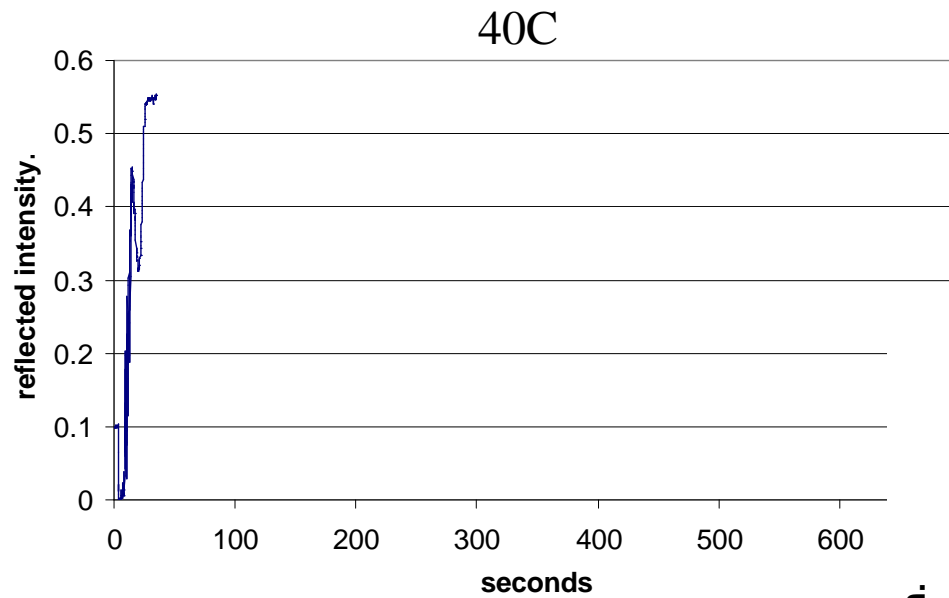
n_2 = film refractive index (~1.55)



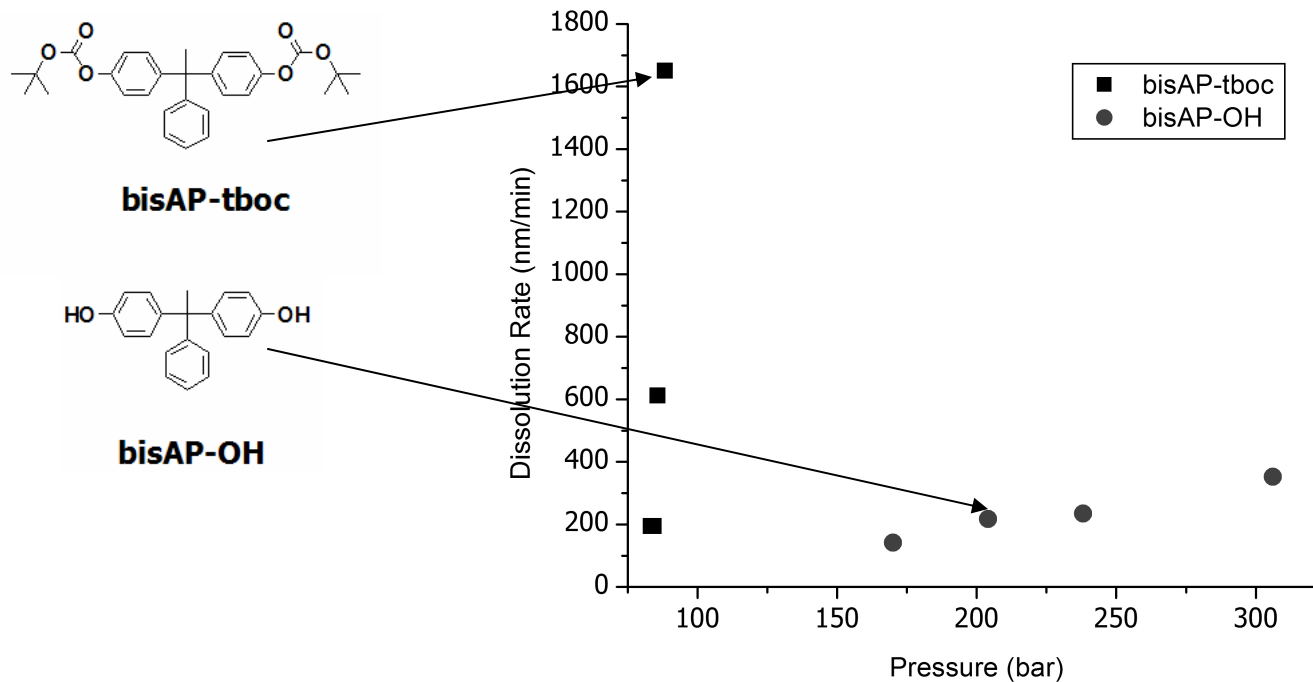
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Increasing pressure



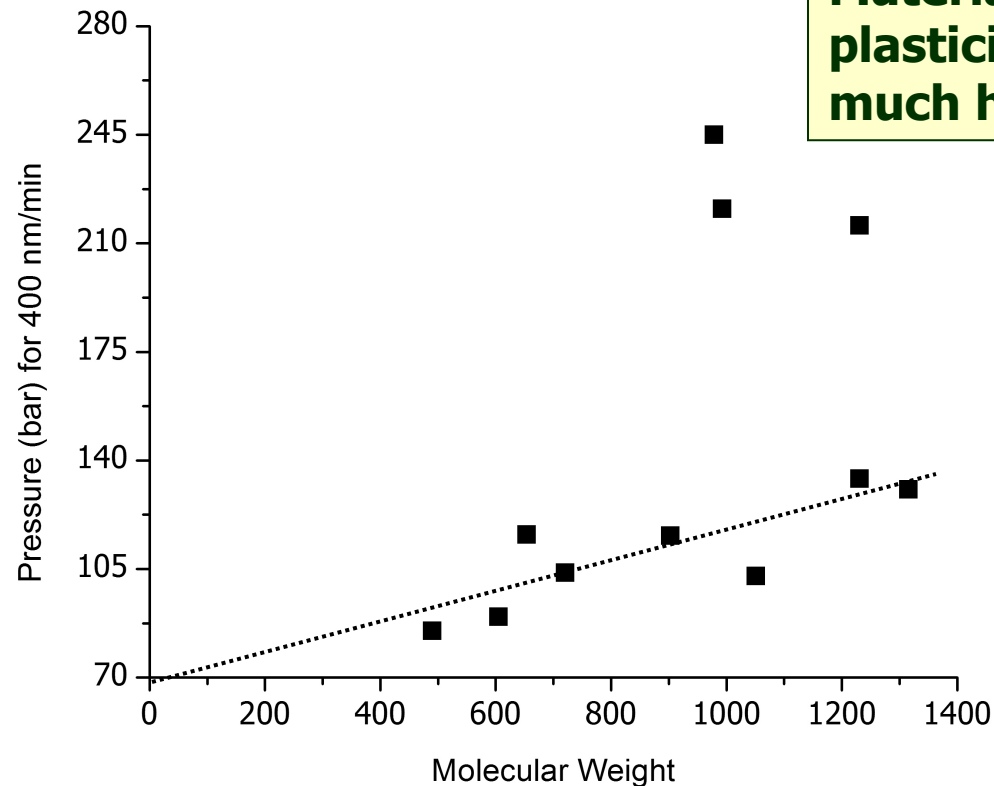
Effects of polarity



- Molecules with less than 3 –OH groups still significantly soluble.
- Effect more pronounced at lower temperatures.
- Indicative of contrast between exposed and unexposed regions.



Effect of molecular weight, Tg



Materials that resist plasticization require much higher pressures.

Necessary pressure to achieve dissolution rate increases predictably with larger MW.

However, photoresists approaching 2000 g/mol still soluble in scCO₂!



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Felix, N. M, et al., *J. Mat. Chem.*, in press.

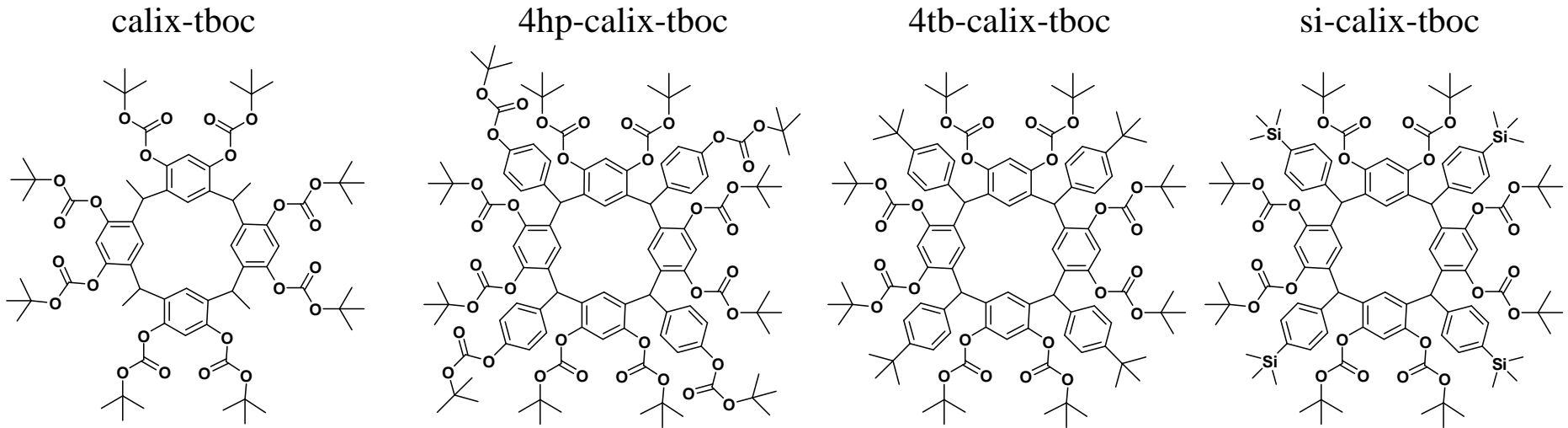
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Going forward

- Methodology in place for predicting, measuring scCO_2 solubility, especially with small molecules
 - Patterning possible with high T_g materials
- Can be expanded to positive-tone materials
 - Need chain-scission type resist materials

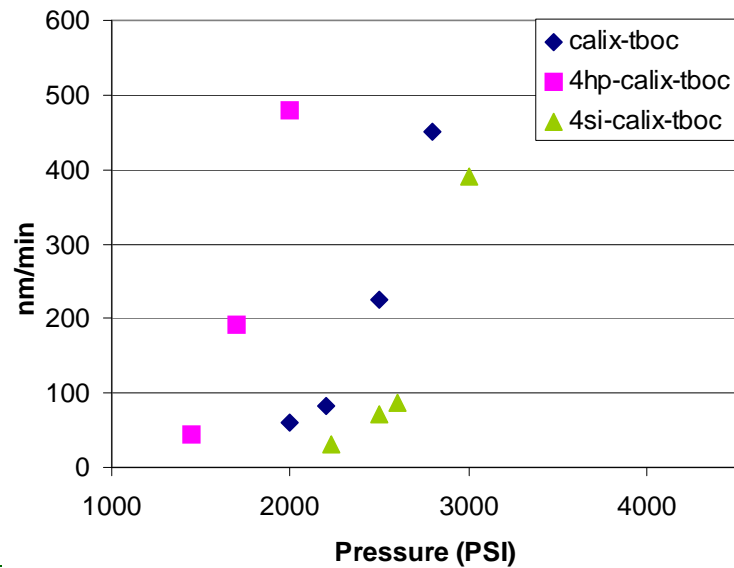


Calix[4]resorcinarenes



Felix, N. M, et al., *manuscript in preparation*.

	T_g (C)
calix-tboc	107
4hp-calix-tboc	84
4tb-calix-tboc	110
4si-calix-tboc	140

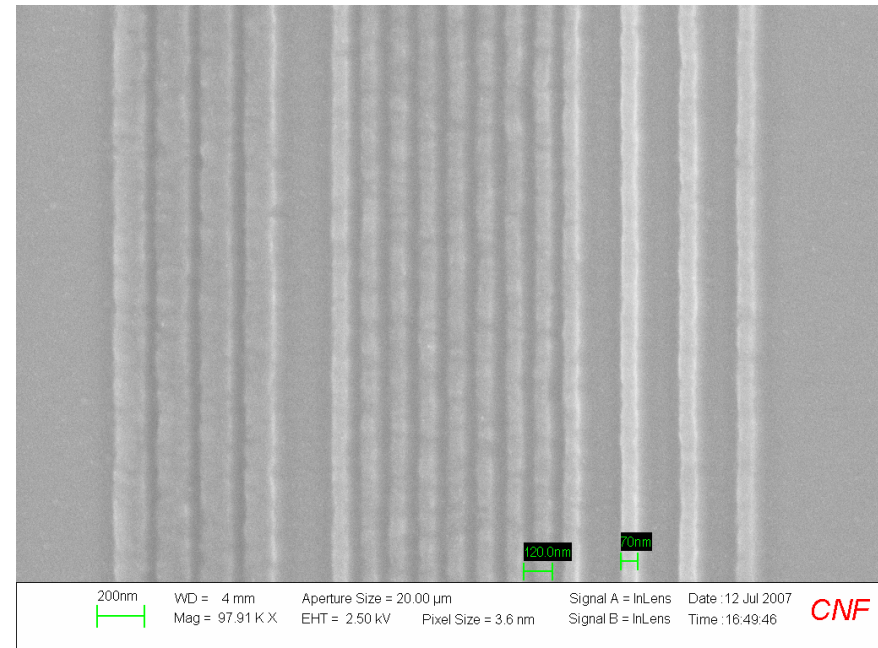
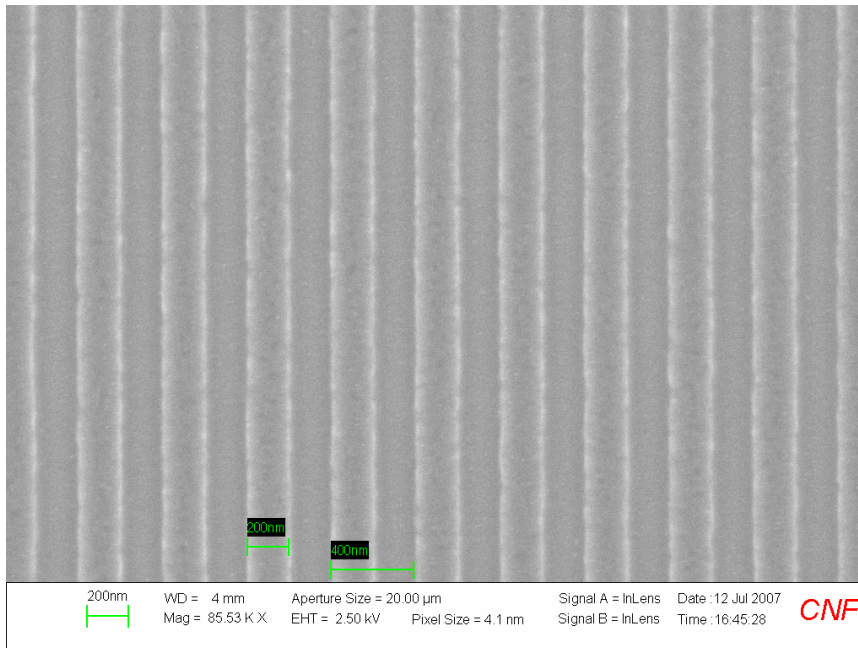


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Patterning

Developed 37C, 2500psi (e-beam)



- As expected, sub-100nm performance shown with calix[4]resorcinarenes developed in scCO₂

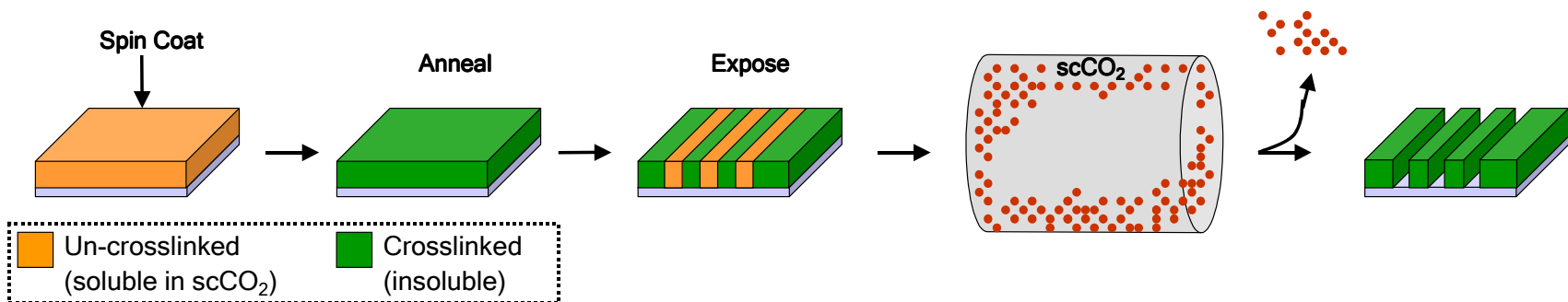


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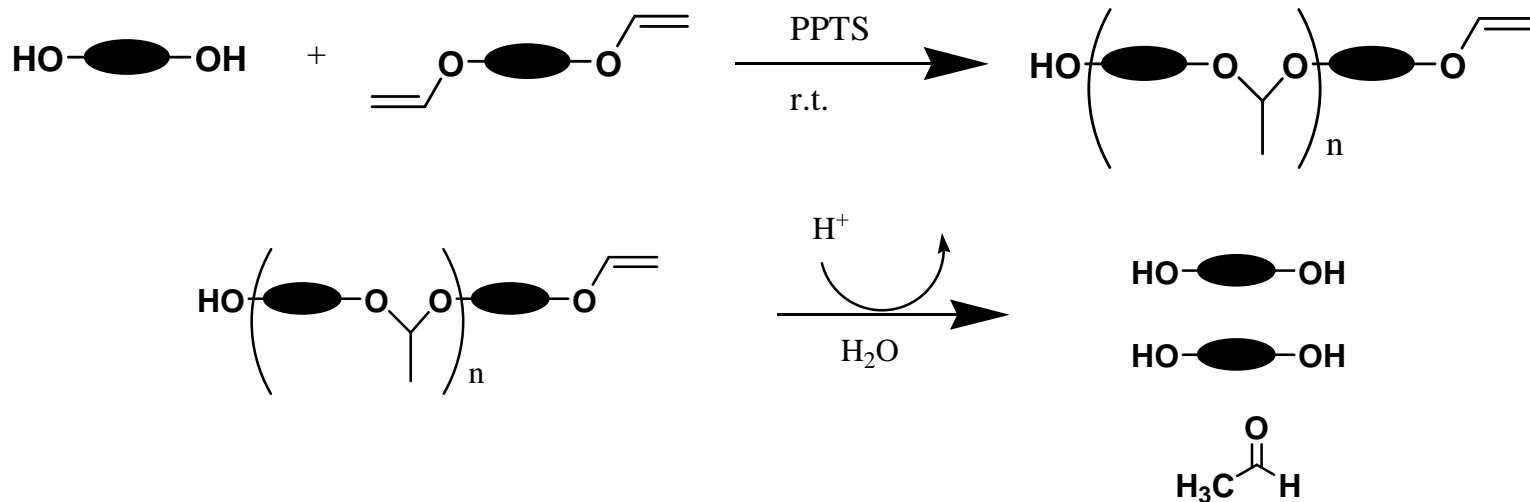
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De-crosslinking Resists for Positive Tone

- PMMA is classic example
 - High resolution e-beam, EUV resist with low LER
 - Problem: low sensitivity
- Acid catalyzed de-crosslinking
 - Improved sensitivity
 - Use acetal bonds to crosslink otherwise scCO_2 soluble species



Acetal-backbone polymers



- Optimal system for scCO₂ development
 - Bisphenol-type compounds shown to be scCO₂-soluble
 - Large changes in molecular weight lead to solubility contrast



Summary

- Along with being environmentally friendly, supercritical CO₂ shows performance advantages.
- Molecular glass photoresists have shown good performance, low LER under EUV patterning.
- Any given molecular glass platform has the potential for both base development and scCO₂ development.
 - Molecules approaching 2000 g/mol significantly soluble
 - < 65nm features shown with select systems
- First report of intrinsic positive-tone system for scCO₂ development.



Acknowledgements

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 - SRC/Sematech ERC for Environmentally Benign Semiconductor Manufacturing
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- Kosuke Tsuchiya
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